

12 inch Ion Beam Etcher

Standard Process



Canon Anelva NC8000

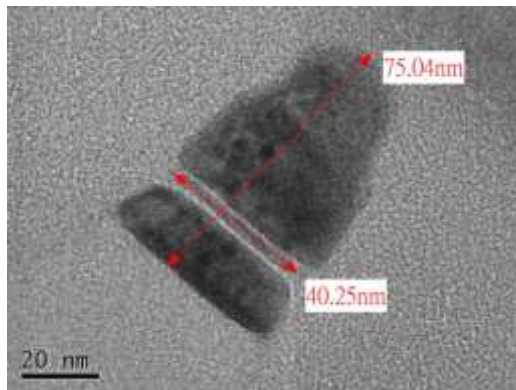
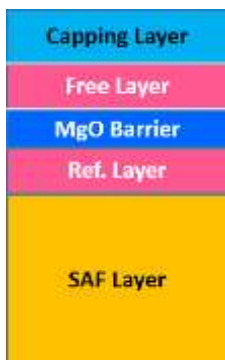
□ Standard Process

- STT & SOT MTJ structure Etching

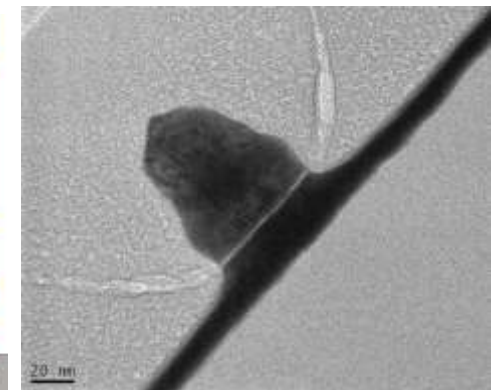
□ Wafer size

- 8" 、 12"
- Chip 、 4" 、 6" (Can't be detected by OES.)

STT MTJ structure

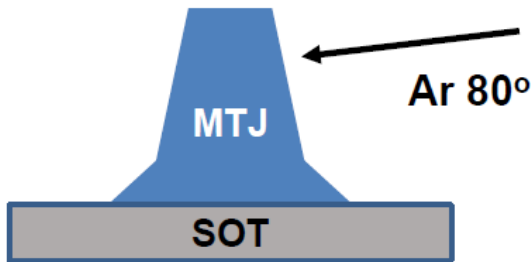


SOT MTJ structure

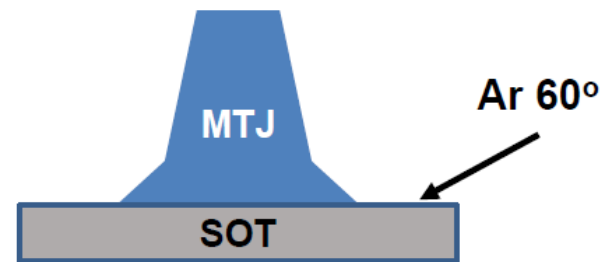


IBE Etching Flow for MTJ Structure

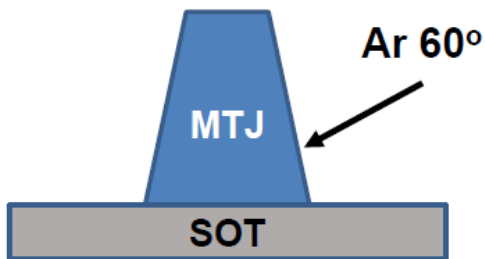
1. MTJ main etch & trimming



2. Clean SOT surface



4. Sidewall cleaning



3. Eliminate footing

